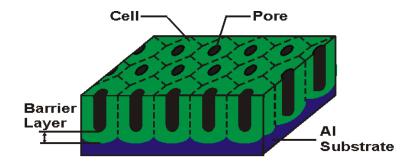
## Session 10a

## Nano-Scale Structures Fabricated using Anodic Aluminum Oxide Templates; Etching and Thermal Evaportaion

#### What is Anodic Porous Alumina?

• Aluminum oxide grown on an Al substrate in an electrolytic cell. The resulting structure consists of an array of **tunable** nanometer-sized pores surrounded by an alumina backbone.

## Motivation General



### **Purpose:**

• To understand the mechanisms involved in the growth and ordering of anodic porous alumina.

## Motivation General

#### **Motivation:**

• Interest in using anodic porous alumina as a nano- template to fabricate nanometer-sized structures (e.g. nanofabrication of quantum dots).

### Why do we want to fabricate nanostructures?

- 1. Fundamental physical interest in the nanometer size regime.

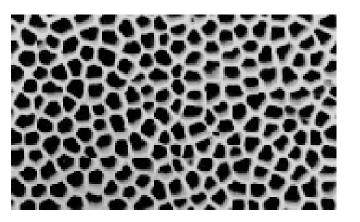
  Properties of nano-sized structures are different from their bulk and molecular counterparts.
- 2. Technological applications as electronic and optical devices.

## **Motivation: Applications**

## 1. Physics:

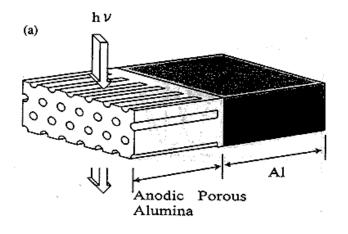
• Explore optical, electrical, and magnetic quantum confinement.

Commercially available
Anopore filter.
http://www.2spi.com/catalog/s
pec\_prep/filter2.html



### 2. Engineering:

- Microfiltration.
- Optical waveguides and photonic crystals for optical circuits.
- Template for carbon nanotube growth for electronic, mechanical applications.
- Ordered arrays of quantum dots for lasers, photodetectors.
- Ultra Large Scale Integration (ULSI) memory devices and Integrated Crcuits (Ics)

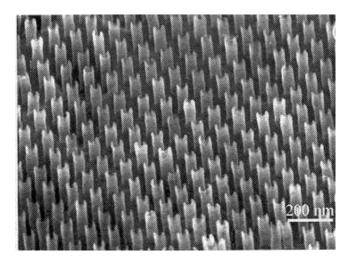


Porous Alumina used as optical waveguide.

H. Masuda, et. *al.*, *Jpn. J. Appl. Phys.* **38**, L1403 (1999).

Ordered arrays of carbon nanotubes fabricated using a porous alumina template.
J. Li, et al., Appl. Phys. Lett.

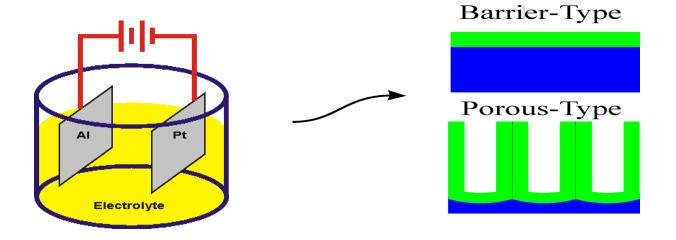
J. Li, et al., Appl. Phys. Lett. **75**(3), 367 (1999).



## Overview of Anodic Oxide Films

#### **Fabrication**

• Anodize aluminum in electrolyte (e.g. Oxalic Acid)



Two main types of anodic oxide films can be grown depending on the nature of the electrolyte:

## 1. Barrier-Type Films:

- Grown Oxide Insoluble in Electrolyte
- Nearly Neutral Electrolytes (pH 5-7)

### 2. Porous-Type Films:

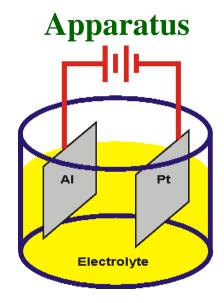
- Grown Oxide Slightly Soluble in Electrolyte
- Aqueous Sulfuric, Oxalic, and Phosphoric Acid Electrolytes

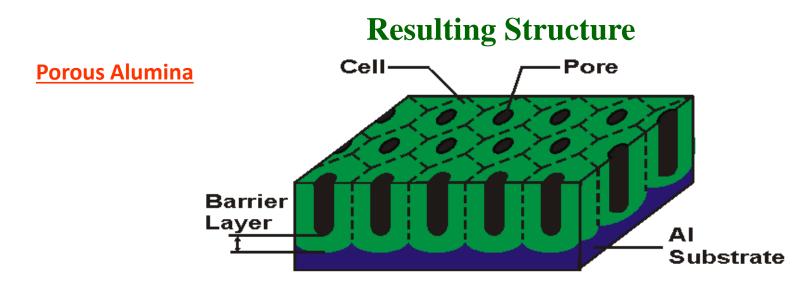
## Historical Time Line

- 1920's Porous alumina starts to be used commercially to protect and finish bulk Al surfaces.
- 1940' s-1960' s With advent of electron microscopes, first characterization of structure of porous alumina, but growth theories are experimentally unsubstantiated.
- 1970 Manchester group does first real experimental work showing pore radius dependence on applied voltage, etc.
- 1992 First "quantitative" theoretical attempt to explain pore growth from first principles by Belorus group.
- 1995 Japanese group discovers pores will self-order into close packed array under the right anodization conditions.
- 1996-Present Use of porous alumina for nano-applications abound.
- 1998 Although mechanism for ordering still not clear, German group proposes one **possible** mechanism.

## Historical Time Line

- Anodize aluminum in electrolyte (e.g. Oxalic Acid).
- Oxide grows at the metal/oxide and oxide/electrolyte interfaces, pores initiate at random positions by field-assisted dissolution at the oxide/electrolyte interface.
- Ordering requires appropriate potentials and long anodization times.
- Ordering results from repulsion between neighboring pores due to mechanical stress at the metal/oxide interface.



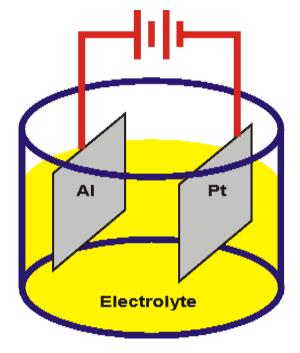


## Barrier-Type Anodic Oxide Films

#### **Growth Mechanism**

- Oxide growth proceeds at the Aluminum anode (+).
- Hydrogen gas is evolved at the Platinum cathode (-).
- The current between the cathode and anode is carried by the electrolyte.
- Oxidation reactions at the Al anode

$$2Al + 3OH^{-} \rightarrow Al_{2}O_{3} + 3H^{+} + 6e^{-}$$
  
 $\{2Al + 3O^{2-} \rightarrow Al_{2}O_{3} + 6e^{-}\}$ 



• Electrolysis of water at aluminum oxide/ electrolyte interface

$$H_2O \to OH^- + H^+(aq)$$
  
 $\{2H_2O \to 2O^{2-} + 4H^+(aq)\}$ 

• Reduction reaction at the cathode:

$$2H^+ + 2e^- \rightarrow H_2 \uparrow$$

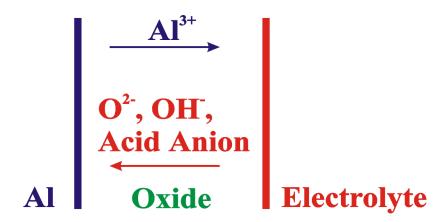
• The overall electrochemical reaction occurring is:

$$2Al + 3H_2O \rightarrow Al_2O_3 + 3H_2$$

## Barrier-Type Anodic Oxide Films

#### **Growth Mechanism**

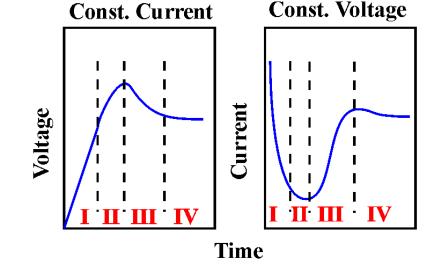
- Oxide growth proceeds at the metal/oxide *and* the oxide/electrolyte interface.
- Growth proceeds due to the motion of ions under the applied field.



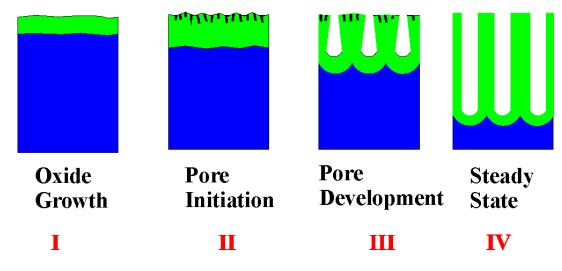
- Growth at the metal/oxide interface is due to oxygen containing anions (mainly OH<sup>-</sup> and O<sup>2-</sup>) moving through interstitial/vacancy sites.
- Growth at the oxide/electrolyte interface is due to Al<sup>3+</sup> cations moving through interstitial/place exchange mechanisms.

## Overview of Film Anodization

- Oxide growth proceeds via ionic conduction and reaction of Al cations and oxygen containing anions under the influence of an applied field.
   (e.g. 2Al<sup>+</sup> + 3OH<sup>-</sup> → Al<sub>2</sub>O<sub>3</sub>+3H<sup>+</sup>+6e<sup>-</sup>)
- Pores initiate at random positions through field-assisted dissolution of the oxide at the oxide/electrolyte interface.



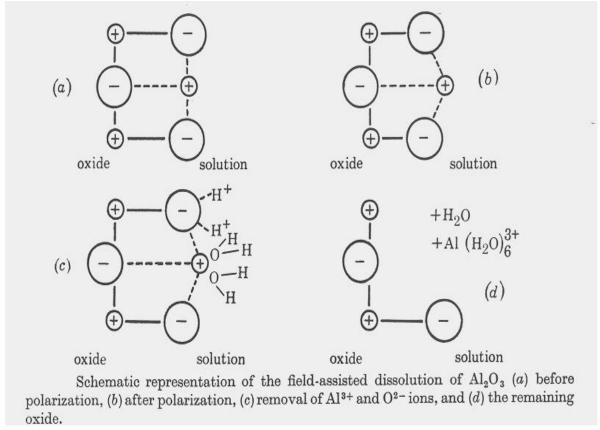
- Initially oxide growth dominates. (I)
- Dissolution becomes competitive, barrier layer thins, and pores initiate. (II)
- Approaches steady state where both mechanisms occur at roughly the same rate. (III and IV)



## Porous-Type Anodic Oxide Films

#### **Field-Assisted Dissolution**

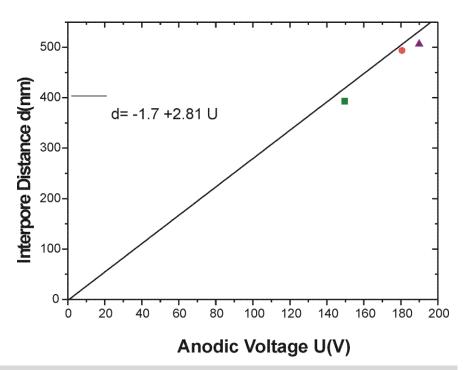
• Application of a field across the oxide polarizes the oxide bonds.



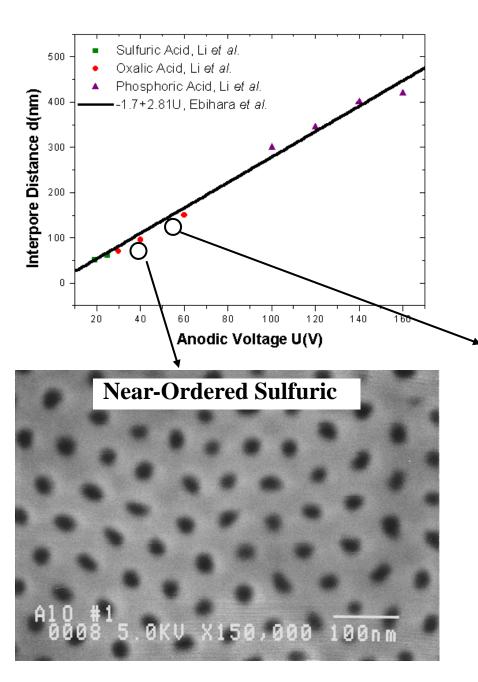
- This polarization effectively lowers the activation energy for dissolution of the oxide.
- This promotes solvation of Al<sup>3+</sup> ions by water molecules and the removal of O<sup>2-</sup> ions by H<sup>+</sup> ions.
- This processes is strongly dependent on the E-field strength.

## Ordered Growth of Porous Alumina

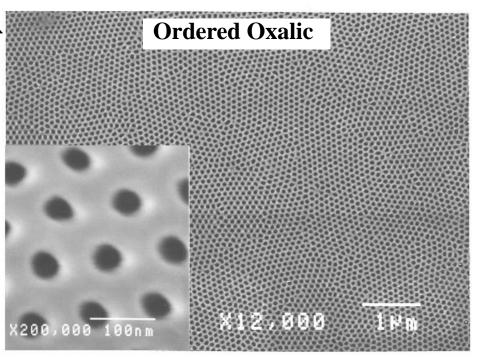
- In 1995, Japanese group found that pores will self-order under the right anodization conditions.
- The two most important conditions are narrow voltage ranges and long anodization times.



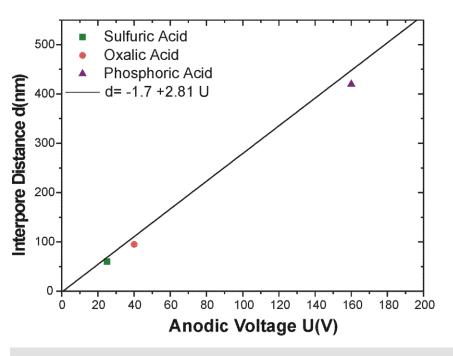
## Ordered Nano-Templates



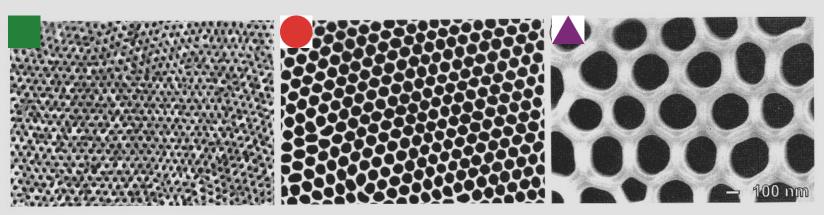
- Tunable diameters and spacings from 20 nm to 500 nm.
- Polycrystalline structure: ordered micron-sized domains, defects at grain boundaries.
- Low temperature growth produces unordered 4-10 nm arrays.



## Ordered Growth of Porous Template



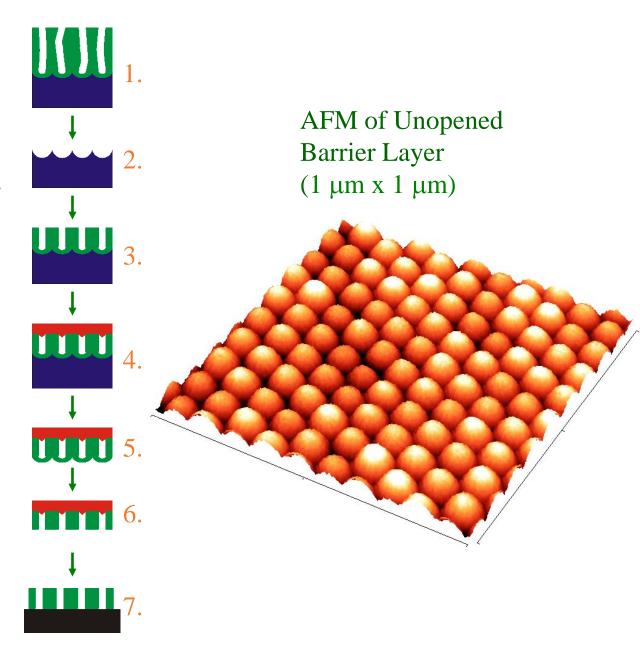
- Ordered pore arrays obtained in three different electrolytes for long anodization times and appropriate voltages (specific for each electrolyte).
- Polycrystalline structure with perfectly ordered domains a few microns in size. Defects occur at grain boundaries.



## Mask Processing

## To create an ordered through-hole mask:

- 1. Anodize for a long time allowing pores to order.
- 2. Chemically remove the alumina in a mixture of phosphoric and chromic acid.
- 3. Anodize for a short time (now pores are ordered).
- 4. Coat top surface of alumina with a polymer (collodion) to protect it from further processing.
- 5. Remove Al Substrate in a saturated HgCl<sub>2</sub> solution.
- 6. Remove the barrier layer in 5 wt.% Phosphoric Acid.
- 7. Remove collodion and place alumina on desired substrate.



## Pattern Transfer Techniques

## 1. Etching Processes

### **Fluorine Beam**

Transfer mask pattern via etching into substrate for ordered arrays of trenches.

### **Ion Beam**

Transfer mask pattern via ion etching into substrate for ordered arrays of trenches or pillars.

### 2. Growth Processes

## **Sputtering and Thermal Deposition**

Transfer mask pattern via deposition onto substrate for ordered arrays of dots.

## F-Etched Array of Si(001) Nano-Holes

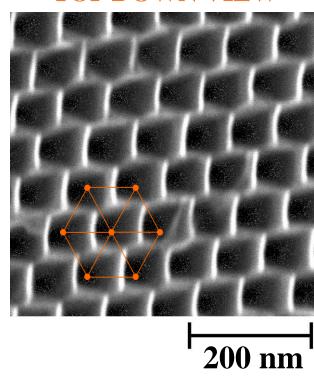
**SAMPLE:** ~500nm thick Free-Standing AAO/Si(001)

**F-ETCH:** 1 min. 20 sec.

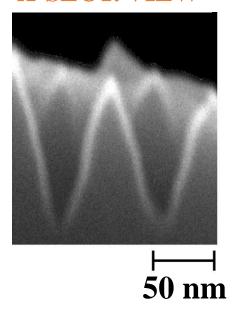
 $T_{SUB} = 250$ °C

**PORES:** Width 70 nm, Depth 100-120 nm

#### **TOP DOWN VIEW**



#### X-SECT. VIEW



• Walls are ~30 nm thick (near top).

**SAMPLE:** ~500nm thick Free-Standing

AAO/GaAs(100)

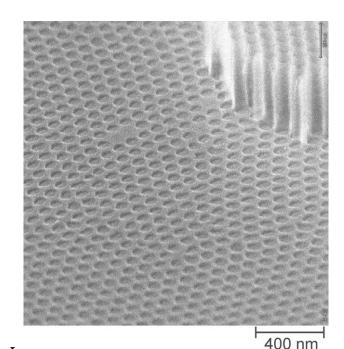
**ION BEAM:**  $500 \text{ eV Ar}^+, 0.05 \text{ mA/cm}^2$ 

Time = 2hrs. 12min.

**PORES:** Width 50 nm, Depth 50-60 nm

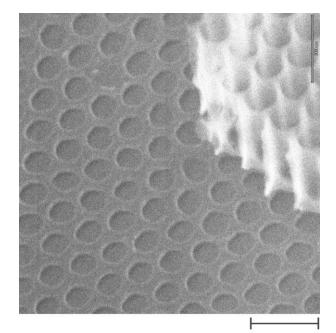
## Ion Etched Array of GaAs Nano-Holes

#### **OBLIQUE VIEW**

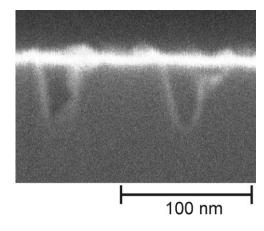


OU NanoLab/NSF NUE/Bumm & Johnson

#### ~TOP DOWN VIEW



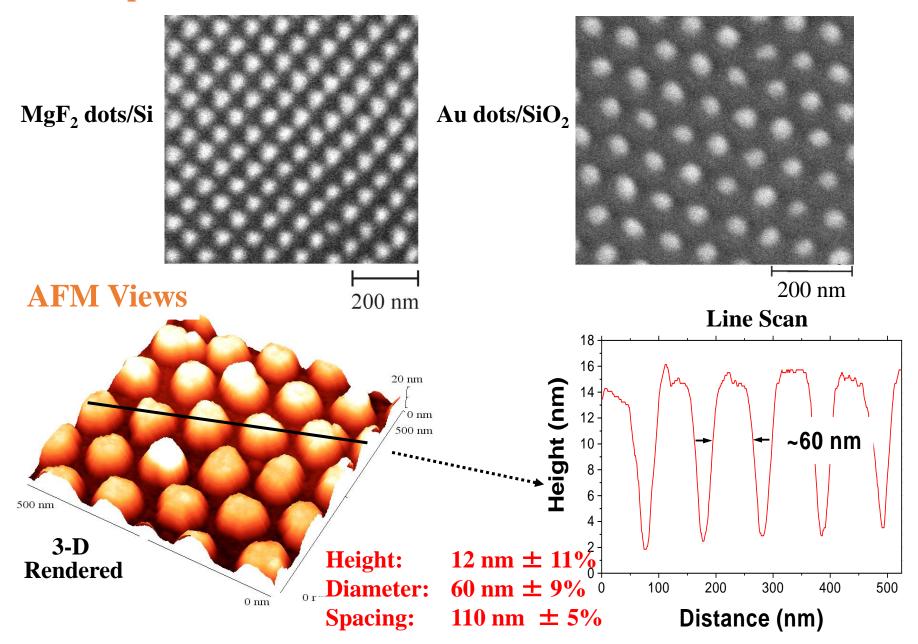
X-SECT. VIEW



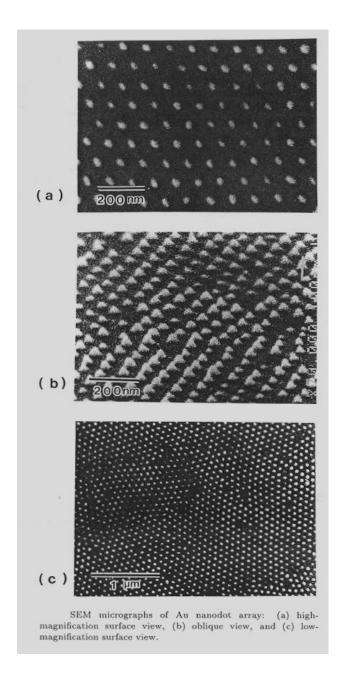
200 nm

## Thermally Evaporated Nano-Dots: MgF<sub>2</sub>

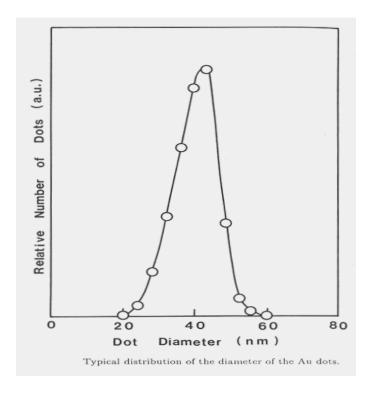
### **SEM Top Views**



## Thermally Evaporated Nano-Dots: Gold



• Porous alumina used as an evaporation mask to grow quantum dots.



H. Masuda *et al.*, *Jpn. J. Appl. Phys.* **35**, L126 (1996).

**SAMPLE:** ~20nm thick Fe dots on GaAs(100).

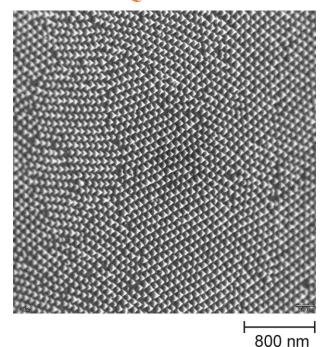
**ION BEAM:**  $500 \text{ eV Ar}^+, 0.05 \text{ mA/cm}^2$ 

Time = 17 min.

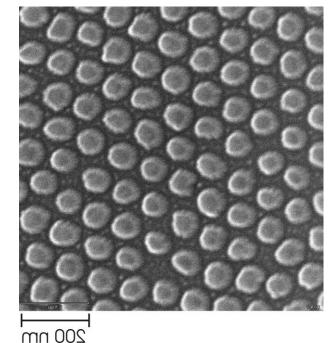
**PILLARS:** Width 50 nm, Height 50 nm

## Ion Etched Array of GaAs Nano-Pillars

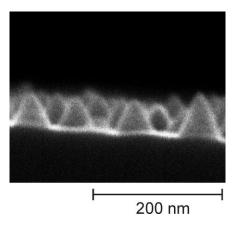




#### **TOP DOWN VIEW**



#### X-SECT. VIEW



Note: No Fe

remaining.

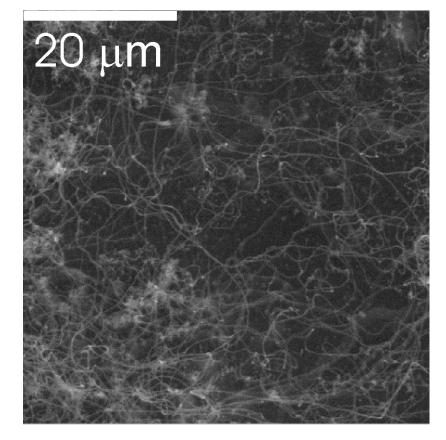
# Evaporated Catalyst Dots For Carbon Nanotube Growth

**SAMPLE:** ~20nm thick Fe catalyst dots on 100nm Ti/Si

**GROWTH:** CVD using Methane gas at 500 Torr, 800°C

**NANOTUBES:** Multi-walled tubes, ~10s of microns long

#### **TOP DOWN VIEW**



 Collaboration with Dr. Shen Zhu of Marshall Space Flight Center.

### Remarks

## **Conclusions**

Fabricated ordered, arrays of nanostructures using porous alumina templates as masks:

- Arrays of 50 nm wide trenches in Si and GaAs by atom-beam and sputter etching.
- Arrays of 50 nm dots of various materials onto substrates by evaporation and sputtering.
- Arrays of nano-pillars in Si and GaAs by etching nano-dot arrays.

## **Future**

- Make pores smaller (to 5 nm) using sulfuric acid electrolytes and low temp. anodization.
- Seed for carbon nanotube growth.
- Explore optical, electrical, and magnetic properties of nanostructures.
- Explore ways to transfer single or arbitrary dot/trench patterns.
- Fabricate such nanostructures *in situ* in multichamber MBE system.